EE 330 Lecture 13

Devices in Semiconductor Processes

- Resistors
- Diodes
- Capacitors
- MOSFETs
- BJTs

Fall 2023 Exam Schedule

Exam 1 Friday Feb 16

Basic Semiconductor Processes

MOS (Metal Oxide Semiconductor)

1. NMOS n-ch

2. PMOS p-ch

3. CMOS n-ch & p-ch

Basic Device: MOSFET

Niche Device: MESFET

Other Devices: Diode

BJT (Bipolar Junction Transistor)

JFET (Junction Field Effect Transistor)

Resistors Capacitors

Schottky Diode

Basic Semiconductor Processes

Bipolar

- 1. T^2L
- 2. ECL
- 3. I^2L
- 4. Linear lcs

Basic Device: BJT (Bipolar Junction Transistor)

Niche Devices: HBT (Heterojunction Bipolar Transistor)

Other Devices: Diode

Resistor Capacitor

Schottky Diode

JFET (Junction Field Effect Transistor)

Basic Semiconductor Processes

Other Processes

- Thin and Thick Film Processes
 - Basic Device: Resistor
- BiMOS or BiCMOS
 - Combines both MOS & Bipolar Processes
 - Basic Devices: MOSFET & BJT
- SiGe
 - BJT with HBT implementation
- SiGe / MOS
 - Combines HBT & MOSFET technology
- SOI / SOS (Silicon on Insulator / Silicon on Sapphire)
- Twin-Well & Twin Tub CMOS
 - Very similar to basic CMOS but more optimal transistor char.

Devices in Semiconductor Processes

- Standard CMOS Process
 - MOS Transistors
 - n-channel
 - p-channel
 - Capacitors
 - Resistors
 - Diodes
 - BJT (decent in some processes)
 - npn
 - pnp
 - JFET (in some processes)
 - n-channel
 - p-channel
- Standard Bipolar Process
 - BJT
 - npn
 - pnp
 - JFET
 - n-channel
 - p-channel
 - Diodes
 - Resistors
 - Capacitors
- Niche Devices
 - Photodetectors (photodiodes, phototransistors, photoresistors)
 - MESFET
 - HBT
 - Schottky Diode (not Shockley)
 - MEM Devices
 - TRIAC/SCR
 - ...

Basic Devices

Standard CMOS Process **MOS Transistors** n-channel p-channel **Capacitors Primary Consideration** Resistors Diodes in This Course BJT (decent in some processes) npn pnp JFET (in some processes) n-channel p-channel **Standard Bipolar Process BJT** npn Some Consideration in pnp **JFET This Course** n-channel p-channel (devices are available in some CMOS processes) Diodes Resistors Capacitors **Niche Devices** Photodetectors (photodiodes, phototransistors, photoresistors) **MESFET HBT** Schottky Diode (not Shockley) **MEM Devices** Some Consideration in TRIAC/SCR **This Course**

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET
- BJT
- JFET
- MESFET

Basic Devices and Device Models



- Diode
- Capacitor
- MOSFET
- BJT

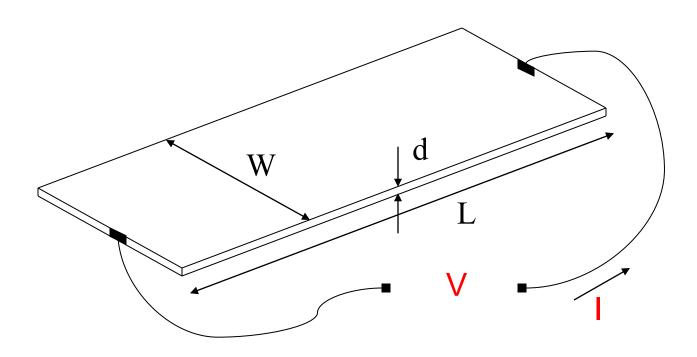
Resistors were discussed when considering interconnects so will only be briefly reviewed here

Resistors

- Generally thin-film devices
- Almost any thin-film layer can be used as a resistor
 - Diffused resistors
 - Poly Resistors
 - Metal Resistors
 - "Thin-film" adders (SiCr or NiCr)
- Subject to process variations, gradient effects and local random variations
- Often temperature and voltage dependent
 - Ambient temperature
 - Local Heating
- Nonlinearities often a cause of distortion when used in circuits
- Trimming possible resistors
 - Laser, links, switches

Have already modeled resistance as an interconnect Modeling is the same as for a resistor so will briefly review

Resistor Model

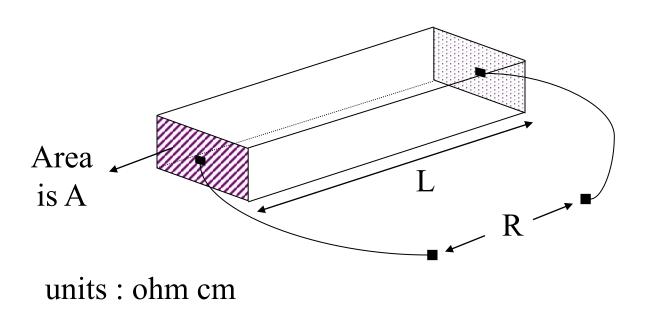


Model:

$$R = \frac{V}{I}$$

Resistivity

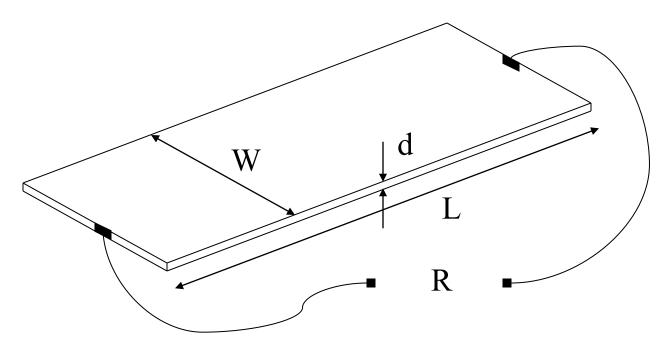
Volumetric measure of conduction capability of a material



$$\rho = \frac{AR}{L}$$

for homogeneous material, $\rho \perp A$, R, L

Sheet Resistance



$$R_{\square} = \frac{RW}{L}$$
 (for d << w, d << L) units : ohms / \square

for homogeneous materials, R_{\pi} is independent of W, L, R

Relationship between ρ and $R_{\mathbb{P}}$

$$R_{\square} = \frac{RW}{L}$$

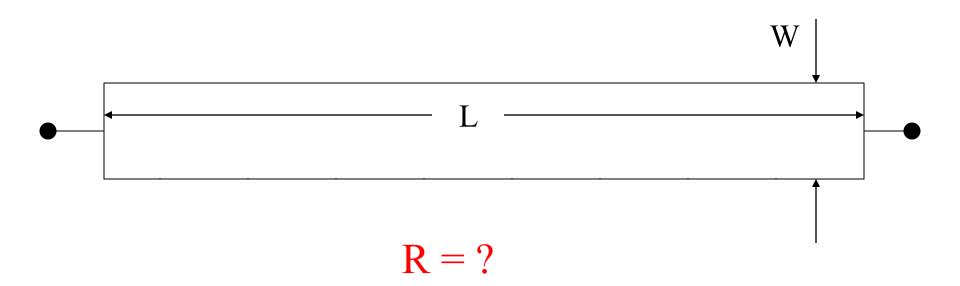
$$\rho = \frac{AR}{L}$$

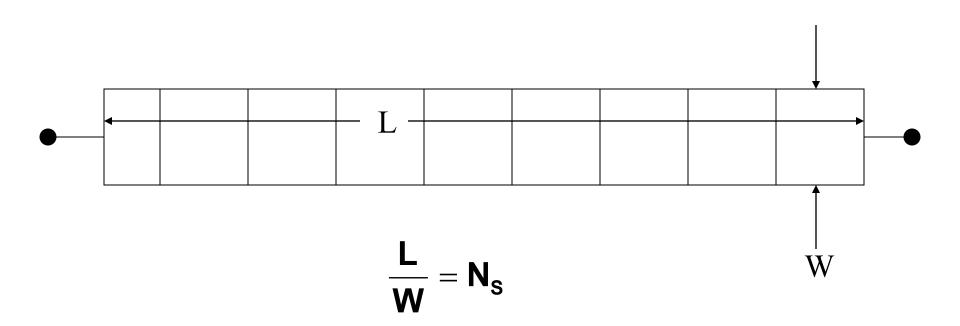
$$\rho = \frac{A}{W}R_{\square}$$

$$A = W \times d$$

$$\rho = \frac{A}{W}R_{\square} = \frac{W d}{W}R_{\square} = d \times R_{\square}$$

Number of squares, N_s, often used instead of L / W in determining resistance of film resistors







R = ?

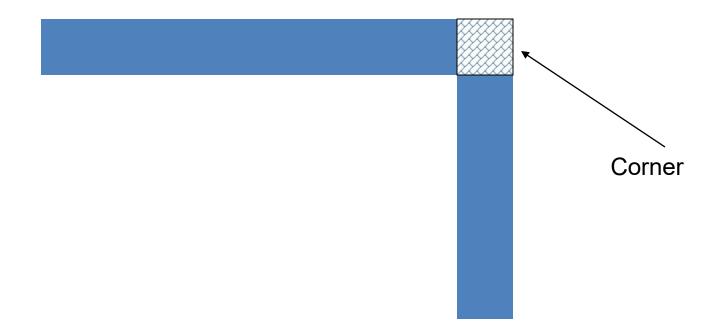


$$R = ?$$

$$N_{S} = 8.4$$

$$R = R_{1}(8.4)$$

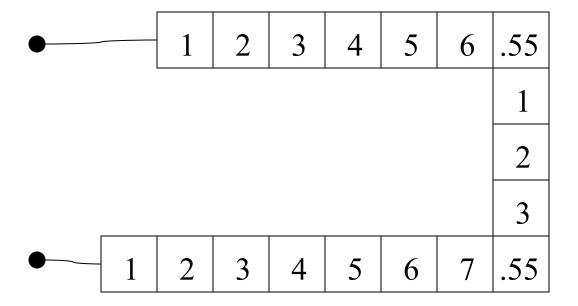
Corners in Film Resistors



Rule of Thumb: .55 squares for each corner

Determine R if $R_{\Box} = 100 \Omega / \Box$





$$N_S$$
=17.1
 $R = (17.1) R_{\Box}$
 $R = 1710 \Omega$

Resistivity of Materials used in Semiconductor Processing

• Cu: $1.7E-6 \Omega cm$

• Al: $2.7E-6 \Omega cm$

• Gold: $2.4E-6 \Omega cm$

• Platinum: $1.1E-5 \Omega cm$

• Polysilicon: 1E-2 to 1E4 Ω cm*

• n-Si: typically .25 to 5 Ω cm* (but larger range possible)

• intrinsic Si: $2.5E5 \Omega cm$

• SiO_2 : E14 Ω cm

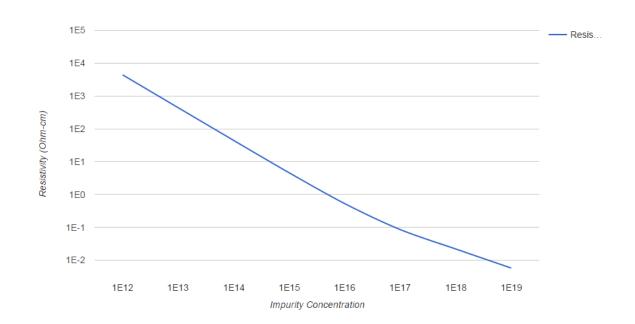
^{*} But fixed in a given process

http://www.cleanroom.byu.edu/ResistivityCal.phtml

Resistivity & Mobility Calculator/Graph for Various Doping Concentrations in Silicon

| Dopant: | Arsenic Boron Phosphorus |
|-------------------------|---|
| Impurity Concentration: | 1e15 (cm ⁻³) |
| | Calculate Export to CSV |
| Mobility: | $1358.6941377290254 \hspace{35pt} [cm^2/V-s]$ |
| Resistivity: | $4.593746148183427 \hspace{3.1em} [\Omega\text{-cm}]$ |
| | |

Calculations are for a silicon substrate.

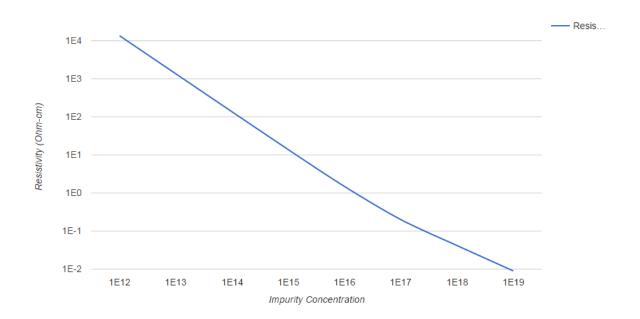


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Resistivity & Mobility Calculator/Graph for Various Doping Concentrations in Silicon

| Dopant: | ArsenicBoronPhosphorus | |
|-------------------------|--|---------------------|
| Impurity Concentration: | 1e15 (cm ⁻³) | |
| | Calculate Export to CSV | |
| Mobility: | 461.9540345952693 [c | m ² /V-s |
| Resistivity: | 13.511075765839905 | l-cm] |
| | | |

Calculations are for a silicon substrate.

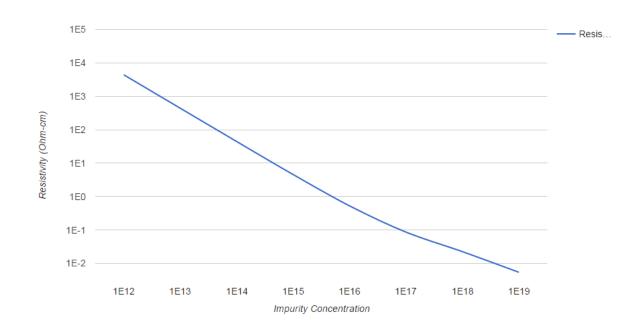


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Resistivity & Mobility Calculator/Graph for Various Doping Concentrations in Silicon

| Dopant: | Arsenic Boron Phosphorus | |
|------------------------|--------------------------|------------------------|
| mpurity Concentration: | 1e15 (cm ⁻³) | |
| | Calculate Export to CSV | |
| Mobility: | 1362.0563795030084 | [cm ² /V-s] |
| Resistivity: | 4.582406466925789 | [Ω-cm] |
| | | |

Calculations are for a silicon substrate.



Temperature Coefficients

Used for indicating temperature sensitivity of resistors & capacitors For a resistor:

$$TCR = \left(\frac{1}{R} \frac{dR}{dT}\right)_{\text{op. temp}} \bullet 10^6 \text{ ppm/}^{\circ}C$$

This differential eqn can easily be solved if TCR is a constant

$$R(T_2) = R(T_1)e^{\frac{T_2 - T_1}{10^6}TCR}$$
 If x is small, $e^x \cong 1 + x$

It follows that If $TCR*(T_2-T_1)$ is small,

$$R(T_2) \approx R(T_1) \left[1 + (T_2 - T_1) \frac{TCR}{10^6} \right]$$

Identical Expressions for Capacitors

Voltage Coefficients

Used for indicating voltage sensitivity of resistors & capacitors

For a resistor:

$$VCR = \left(\frac{1}{R}\frac{dR}{dV}\right)_{\text{ref voltage}} \bullet 10^6 \text{ ppm/V}$$

This diff eqn can easily be solved if VCR is a constant

$$\mathbf{R}(\mathbf{V_2}) = \mathbf{R}(\mathbf{V_1}) e^{\frac{\mathbf{V_2} - \mathbf{V_1}}{10^6} \mathbf{VCR}}$$

It follows that If $VCR*(V_2-V_1)$ is small,

$$R(V_2) \approx R(V_1) \left[1 + (V_2 - V_1) \frac{VCR}{10^6} \right]$$

Identical Expressions for Capacitors

Temperature and Voltage Coefficients

- Temperature and voltage coefficients often quite large for diffused resistors
- Temperature and voltage coefficients often quite small for poly and metal film (e.g. SiCr) resistors

V V

| Type of layer | Sheet Resistance Ω/□ | Accuracy (absolute) | Temperature Coefficient ppm/°C | Voltage Coefficient ppm/V |
|------------------|----------------------------|---------------------|--------------------------------------|---------------------------------|
| n + diff | 30 - 50 | 20 - 40 | 200 - 1K | 50 - 300 |
| p + diff | 50 -150 | 20 - 40 | 200 - 1K | 50 - 300 |
| n - well | 2K - 4K | 15 - 30 | 5K | 10K |
| p - well | 3K - 6K | 15 - 30 | 5K | 10K |
| pinched n - well | 6K - 10K | 25 - 40 | 10K | 20K |
| pinched p - well | 9K - 13K | 25 - 40 | 10K | 20K |
| first poly | 20 - 40 | 25 - 40 | 500 - 1500 | 20 - 200 |
| second poly | 15 - 40 | 25 - 40 | 500 - 1500 | 20 - 200 |

(relative accuracy much better and can be controlled by designer)

MOS Passive RC Component Typical Performance Summary

| Component Type | Range of Values | Absolute Accuracy | Relative Accuracy | Temperature Coefficient | Voltage Coefficient |
|------------------------|--|----------------------|----------------------|----------------------------|------------------------|
| MOSFET gate Cap. | 6-7 fF/μm ² | 10% | 0.1% | 20ppm/°C | ±20ppm/V |
| Poly-Poly Capacitor | $0.3 \text{-} 0.4 \text{ fF/} \mu\text{m}^2$ | 20% | 0.1% | 25ppm/°C | $\pm 50 ppm/V$ |
| Metal-Metal Capacitor | 0.1 -1fF/ μ m ² | 10% | 0.6% | -40ppm/°C | ±1ppm/V |
| Diffused Resistor | 10-100 Ω/sq. | 35% | 2% | 1500ppm/°C | 200ppm/V |
| Ion Implanted Resistor | 0.5 -2 k Ω /sq. | 15% | 2% | 400ppm/°C | 800ppm/V |
| Poly Resistor | 30-200 Ω/sq. | 30% | 2% | 1500ppm/°C | 100ppm/V |
| n-well Resistor | 1-10 kΩ/sq. | 40% | 5% | 8000ppm/°C | 10kppm/V |
| Top Metal Resistor | 30 mΩ/sq. | 15% | 2% | 4000ppm/°C | - |
| Lower Metal Resistor | 70 mΩ/sq. | 28% | 3% | 4000ppm/°C | |

Table 2.4-1 Approximate Performance Summary of Passive Components in a 0.18 μm CMOS Process

| Component Type | Typical Value | Typical Matching Accuracy | Temperature Coefficient | Voltage Coefficient |
|--|---------------------------------|------------------------------|----------------------------|------------------------|
| MiM capacitor | $1.0 \text{ fF/}\mu\text{m}^2$ | 0.03% | 50 ppm/°C | 50 ppm/V |
| MOM capacitor | $0.17 \text{ fF/}\mu\text{m}^2$ | 1% | 50 ppm/°C | 50 ppm/V |
| P ⁺ Diffused resistor (nonsilicide) | 80–150 Ω/□ | 0.4% | 1500 ppm/°C | 200 ppm/V |
| N ⁺ Diffused resistor (non-silicide) | 50–80 Ω/□ | 0.4% | 1500 ppm/°C | 200 ppm/V |
| N ⁺ Poly resistor (non-silicide) | 300 Ω/□ | 2% | −2000 ppm/°C | 100 ppm/V |
| P ⁺ Poly resistor | | | | |
| (non-silicide) | 300 Ω/□ | 0.5% | −500 ppm/°C | 100 ppm/V |
| P Poly resistor | | | • • • • • • | 11 |
| (non-silicide) | 1000 Ω/□ | 0.5% | −1000 ppm/°C | 100 ppm/V |
| n-well resistor | 1–2 kΩ/□ | | 8000 ppm/°C | 10k ppm/V |

MOS Passive RC Component Performance Summary

| Component Type | Range of Values | Absolute Accuracy | Relative Accuracy | Temperature Coefficient | Voltage Coefficient |
|---|--------------------------------|----------------------|----------------------|----------------------------|------------------------|
| Poly-oxide-semi- conductor Capacitor | 0.35-0.5 fF/μm ² | 10% | 0.1% | 20ppm/°C | ±20ppm/V |
| Poly-Poly Capacitor | 0.3-0.4 fF/μm ² | 20% | 0.1% | 25ppm/°C | ±50ppm/V |
| Diffused Resistor | 10-100 Ω/sq. | 35% | 2% | 1500ppm/°C | 200ppm/V |
| Ion Implanted Resistor | 0.5-2 kΩ/sq. | 15% | 2% | 400ppm/°C | 800ppm/V |
| Poly Resistor | 30-200 Ω/sq. | 30% | 2% | 1500ppm/°C | 100ppm/V |
| n-well Resistor | 1-10 kΩ/sq. | 40% | 5% | 8000ppm/°C | 10kppm/V |

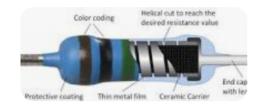
| Layer | R/□ [Ω/□] | T _C [ppm/°C] @ T = 25 °C | V _c [ppm/V] | B _c [ppm/V] |
|--------------|-----------|--|------------------------|------------------------|
| N+ poly | 100 | -800 | 50 | 50 |
| P+ poly | 180 | 200 | 50 | 50 |
| N+ diffusion | 50 | 1500 | 500 | -500 |
| P+ diffusion | 100 | 1600 | 500 | -500 |
| N-well | 1000 | -1500 | 20,000 | 30,000 |

Lingkai Kong

EECS240

How does TCR of Integrated Resistors Compare with Low-Cost Discrete Resistors?

Metal film resistors are available with tolerances of 0.1, 0.25, 0.5, 1 and 2%. The temperature coefficient of resistance (TCR) is usually between 50 and 100 ppm/°C.



Integrated resistors typically have a much larger TCR but there are some special processes that provide resistors with excellent thermal stability (\$\$\$) Example: Determine the percent change in resistance of a 5K Polysilicon resistor as the temperature increases from 30°C to 60°C if the TCR is constant and equal to 1500 ppm/°C

$$R(T_{2}) \cong R(T_{1}) \left[1 + (T_{2} - T_{1}) \frac{TCR}{10^{6}} \right]$$

$$R(T_{2}) \cong R(T_{1}) \left[1 + (30^{\circ}C) \frac{1500}{10^{6}} \right]$$

$$R(T_{2}) \cong R(T_{1}) [1 + .045]$$

$$R(T_2) \cong R(T_1)[1.045]$$

Thus the resistor increases by 4.5%

Did not need R(T₁) to answer this question!

What is $R(T_1)$ as stated in this example ? 5K? It is around 5K but if we want to be specific, would need to specify T

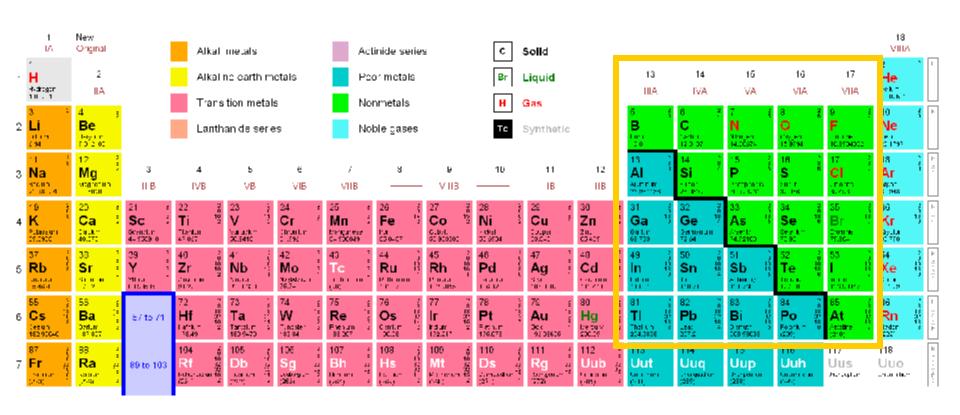
Basic Devices and Device Models

Resistor

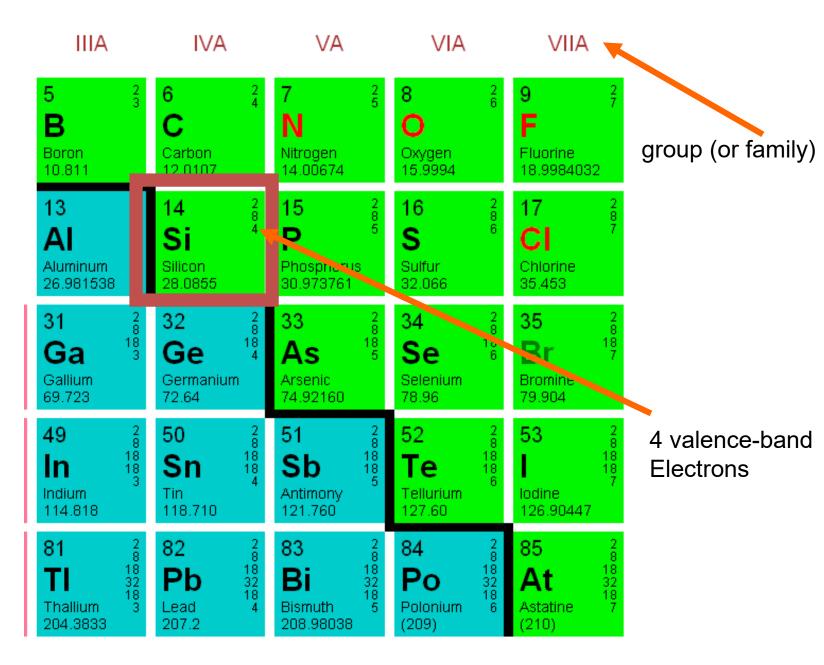


- Capacitor
- MOSFET
- BJT

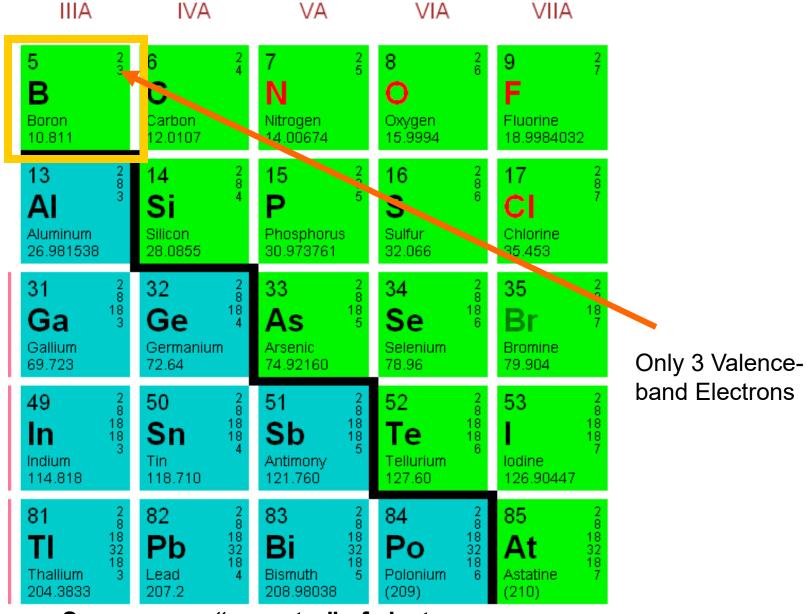
Periodic Table of the Elements



| IIIA | IVA | VA | VIA | VIIA |
|---|---|--|--|---|
| 5 2 8 Boron 10.811 | 6 2 C Carbon 12.0107 | 7 2 N Nitrogen 14.00674 | 8 2 6 Oxygen 15.9994 | 9 ² / ₇ Fluorine 18.9984032 |
| 13 2 8 3 3 Aluminum 26.981538 | 14 2 Si Silicon 28.0855 | 15 2 8 5 P Phosphorus 30.973761 | 16 | 17 2 8 7 CI Chlorine 35.453 |
| 31 2 8 18 3 18 3 Gallium 69.723 | 32 8 18 18 4 Germanium 72.64 | 33 As Arsenic 74.92160 | 34 | 35 Br Bromine 79.904 |
| 49 8 18 18 18 18 18 18 18 18 18 18 18 18 1 | 50 Sn 18 18 18 18 18 18 18 18 18 | 51 Sb Antimony 121.760 | 52 2 8 18 18 18 18 18 18 18 18 18 18 18 18 1 | 53 2 8 18 18 18 18 7 lodine 126.90447 |
| 81 2 8 18 18 32 18 18 32 18 18 32 204.3833 | 82 2 Pb 18 18 32 18 Lead 4 207.2 | 83 2 8 Bi 18 32 18 Bismuth 5 208.98038 | 84 2 8 18 32 18 90 6 (209) | 85 2 8 At 18 32 18 Astatine 7 (210) |



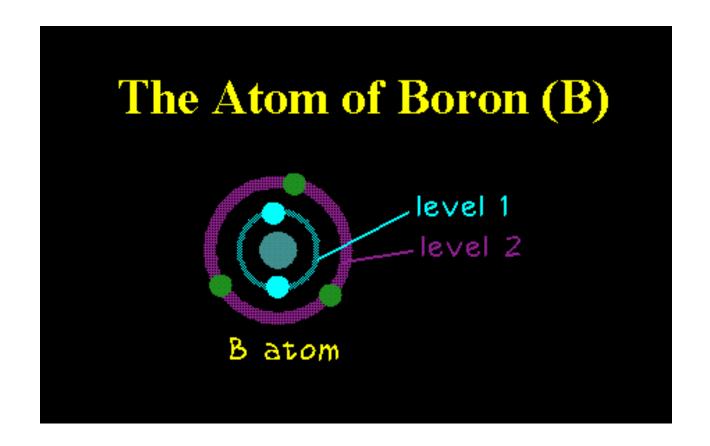
All elements in group IV have 4 valence-band electrons



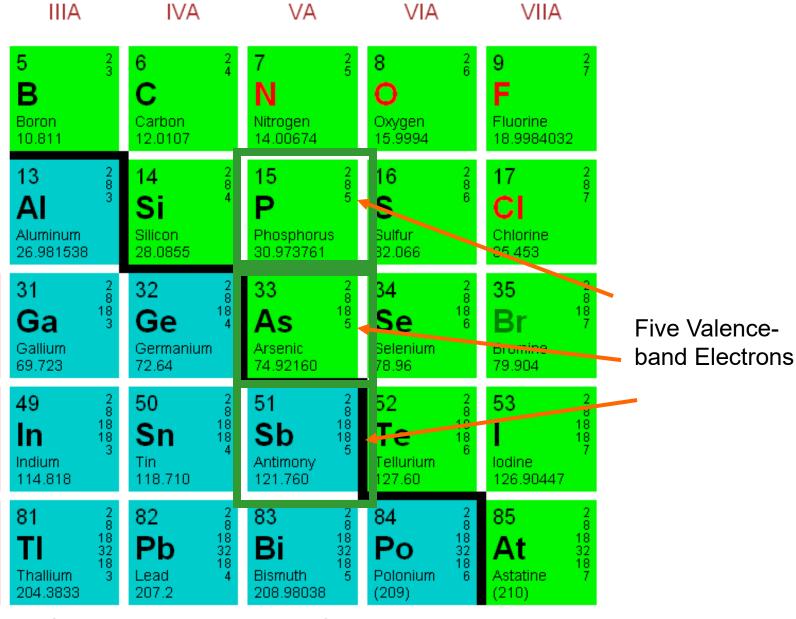
Serves as an "acceptor" of electrons

Acts as a p-type impurity when used as a silicon dopant

All elements in group III have 3 valence-band electrons



http://www.oftc.usyd.edu.au/edweb/devices/semicdev/doping4.html

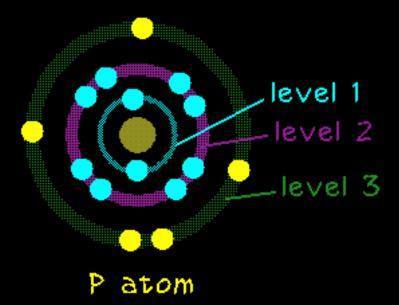


Serves as an "donor" of electrons

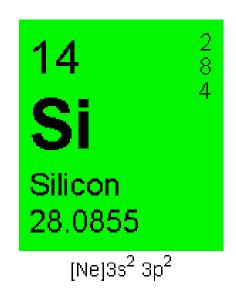
Acts as an n-type impurity when used as a silicon dopant

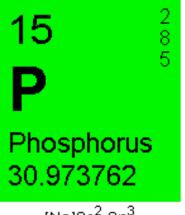
All elements in group V have 5 valence-band electrons

The Atom of Phosphorus (P)

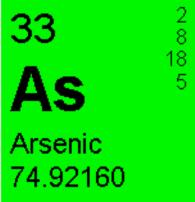




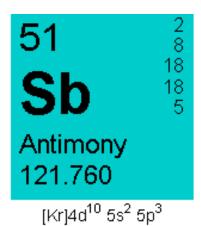




_{[Na12a}2 aa3



[Ar]3d¹⁰ 4s² 4p³



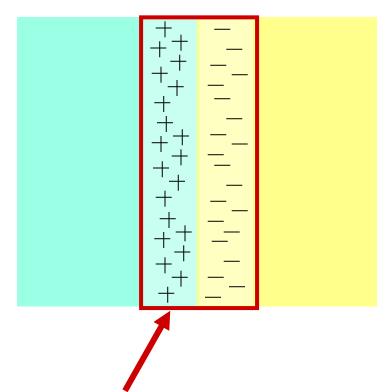
Silicon Dopants in Semiconductor Processes

B (Boron) widely used dopant for creating p-type regions

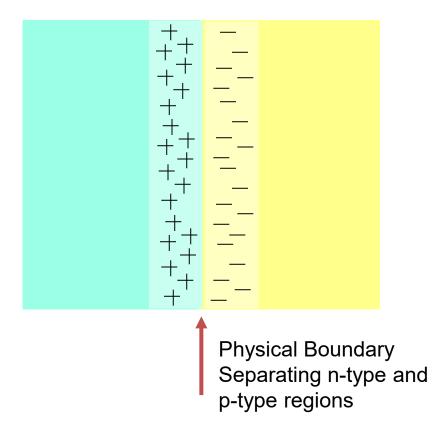
P (Phosphorus) widely used dopant for creating n-type regions (bulk doping, diffuses fast)

As (Arsenic) widely used dopant for creating n-type regions (Active region doping, diffuses slower)

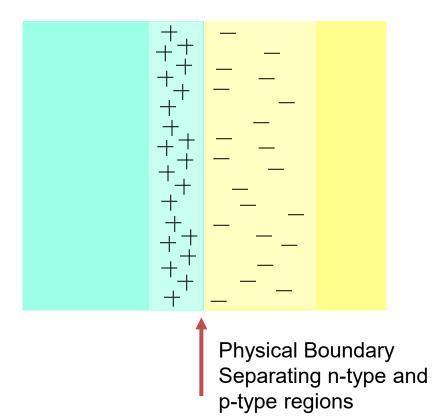
Diodes (pn junctions)



Depletion region created that is ionized but void of carriers



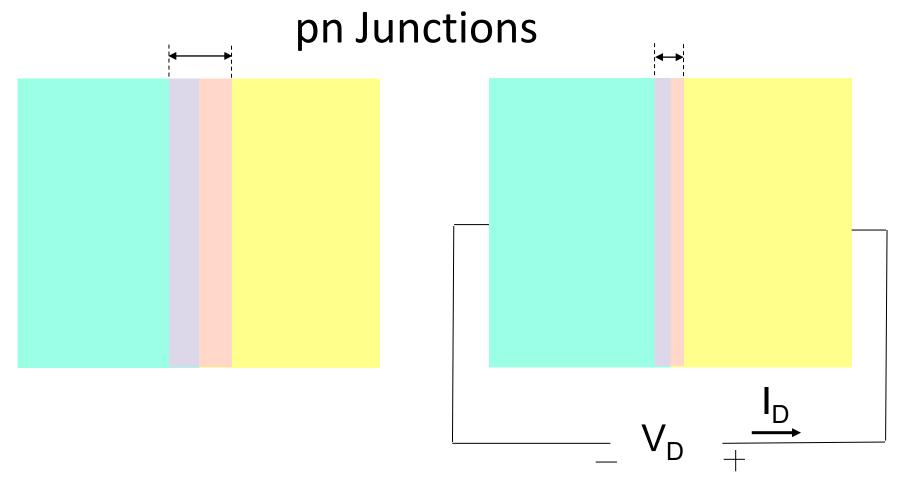
If doping levels identical, depletion region extends equally into n-type and p-type regions



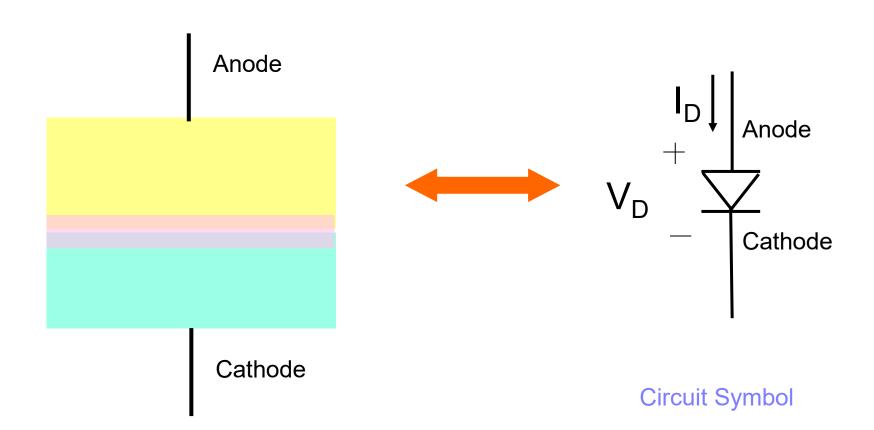
Extends farther into p-type region if p-doping lower than n-doping

Physical Boundary Separating n-type and p-type regions

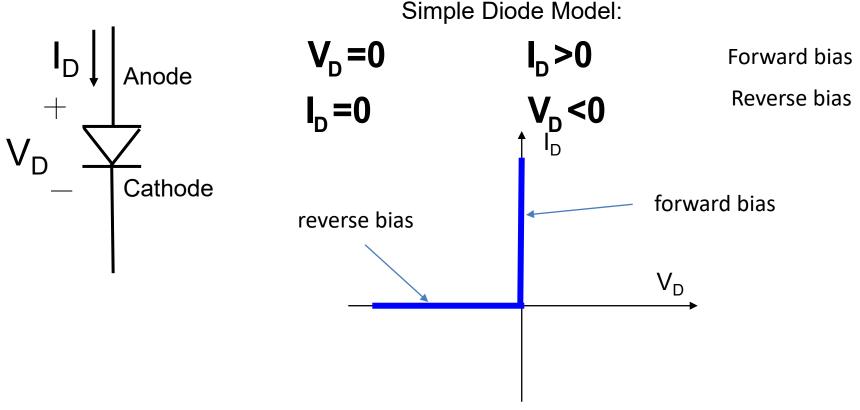
Extends farther into n-type region if n-doping lower than p-doping



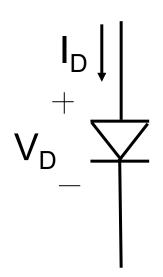
- Positive voltages across the p to n junction are referred to forward bias
- Negative voltages across the p to n junction are referred to reverse bias
- As forward bias increases, depletion region thins and current starts to flow
- Current grows very rapidly as forward bias increases
- Current is very small under revere bias

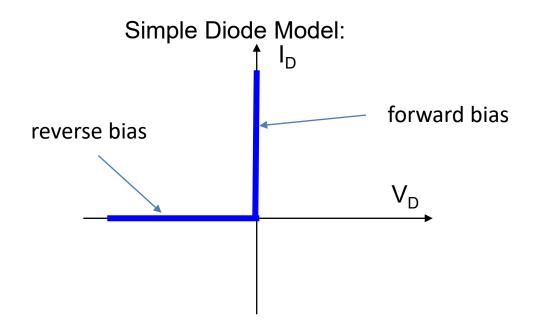


- As forward bias increases, depletion region thins and current starts to flow
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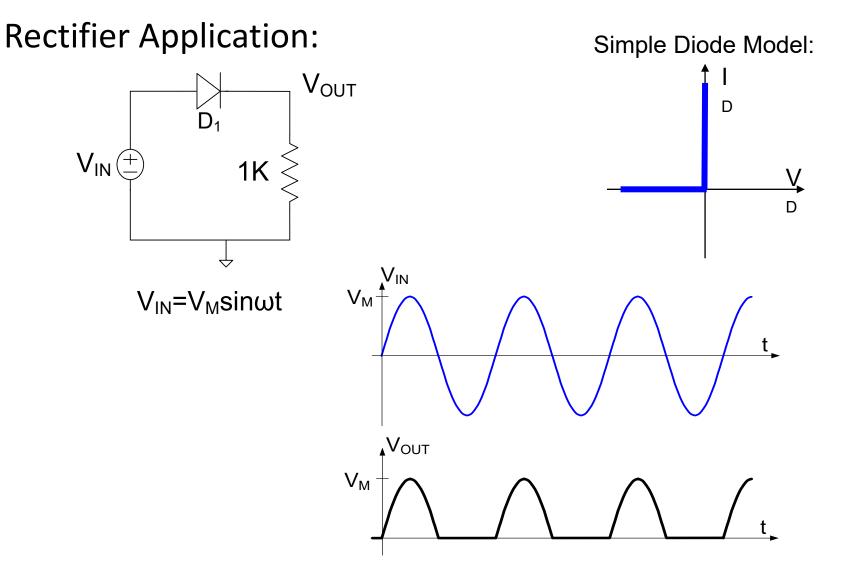


Simple model often referred to as the "Ideal" diode model





pn junction serves as a "rectifier" passing current in one direction and blocking it in the other direction



Analysis based upon "passing current" in one direction and "blocking current" in the other direction



Stay Safe and Stay Healthy!

End of Lecture 13